

Gene	Forward Primer	
ALOX15	GACGCTGGAGACGGTGATG	900 nM
ALOX5	GTGGGCATGTGCAGATGGT	900 nM
ALOX5AP	AATGGGCGGAGCTTCCA	900 nM
ARG1	TACTGGGCGGAGACCACAGT	300 nM
BCL6	GAAAATAATATTGCTTCTTCTCCTATGTGT	900 nM
BDKRB2	GCGCAGCTGGATGGTGTT	100 nM
BLR1	ATCTCTCTGGGCTTCCACAAGA	900 nM
C19orf10	CTTGGACAGCTCAGCCTTGAA	900 nM
CCL11	TCTCCACAGCCCTTCTGTGTCT	900 nM
CCL16	GGGCTACAAAAGGCCTTCA	900 nM
CCL17	AGGATGCCCATGCAGCTC	900 nM
CCL19	TACTGGCCCTCAGCCTGCTA	900 nM
CCL2	GCGGCTGATGAGCTACAGAAG	300 nM
CCL20	GCTCCTGGCTGCTTTGATG	900 nM
CCL21	GTTGCCCATCCCAGCTAT	200 nM
CCL22	CCCTCGTCCTCCTTGCTATG	900 nM
CCL23	GCATTTCTGAACTTGCTCGTCAT	900 nM
CCL24	GCAGCTGTGGGTCCAGAAGT	900 nM
CCL25	TGCTATCCATGCTCAAGGTGC	900 nM
CCL26	CCCAGCAGGCTGTGATATTCA	900 nM
CCL27	TGGAAGTGCAGGAAGCTGATG	900 nM
CCL28	TGAATACATGTGCGCTTCAGAGA	900 nM
CCL3	CCTGTCACCTCCACAGCTACCT	900 nM
CCL4	TCTGCTCTCCAGCGCTCTC	900 nM
CCL5	TGGCAGCAGTCGTCTTTATCA	300 nM
CCL8	CCTTCAAGAACTGGAGAGCTACAC	900 nM
CCR1	AACCCCGTGCCAGAAGGTA	900 nM
CCR10	AGGGATGGAGTATGGGAAGTGTC	900 nM
CCR2	CAGGGCTGTATCACATTGGTTATT	900 nM
CCR3	ACAATGTTCTGCATCTGACCTAAAAT	900 nM
CCR4	TTCACTTCCAGGGCTTTTGTTT	900 nM
CCR5	GCACAGCTCAGCTGGTCAGA	900 nM
CCR6	CCTGCACTGCTGCCTCAA	900 nM
CCR7	CGACACGTACCTGCTCAACTTG	900 nM
CCR8	TGCGACTTTTCTGGAATATTTCTG	900 nM
CD274	TCAGATCACAGATGTGAAATTGCA	900 nM
CD276	CCCTTGACCGGCAACGT	900 nM
CD28	AAGGGATGCCCGGAACTC	300 nM
CD38	TGTCCAAAAGTTTTGCAGAAAAT	900 nM
CD4	ACCTCTCGCCTCGATTCTGA	300 nM
CD40	CCACCTGGAATAGAGAGAAACTGT	900 nM
CD40LG	GAAATGCACAAAGGCGATCA	300 nM
CD69	GGATACCAGACGAAATGCTATTTTATT	900 nM
CD80	ATGGAGAAGAATTAATGCTACCAACAC	900 nM
CD86	TGGGTCGCACAAGCTTTGA	900 nM
CD8A	GAGCAACTCGTTTTGTATTTTCTG	300 nM
CD8B1	GGCTGAGTGTGGTTGATGTCTTT	300 nM
CFTR	CCCTATGTCAACCCTCAACACA	900 nM

CHI3L1	TGGAATGATGTGACGCTCTATGA	900 nM
CHI3L2	TCTGCAAGGCGCCAAGAT	900 nM
CHIA	TGGTTTCCACTGCGGAGAA	900 nM
CHIT1	CTGGACCGGTCCAGGTAATAG	900 nM
CLCA1	CATTGATACTGTGGTTGAATTCTGTAAA	900 nM
CLEC10A	CTCGGAGGAGCATTTCAGAGTAG	900 nM
CMA1	GACCGTCGGATGCAAAGC	900 nM
CMKOR1	CCTGGAGGTTTTATATGGTGATTTG	900 nM
CTLA4	TGAGTTGACCTTCCTTGATGACTCTA	900 nM
CX3CL1	CTCAGTACTTCCATCCCCGACT	900 nM
CX3CR1	TGCACTCTTTCTCCTCCCTTA	900 nM
CXCL10	TTGAAATGATTCTGCAAGTCAA	900 nM
CXCL11	TTCAAGGCTTCCCCATGTTC	900 nM
CXCL12	TCCTGCCATGGGTGTCAAG	900 nM
CXCL14	TCATCACCACCAAGAGCATGTC	900 nM
CXCL16	TCATCCCCACCAGTGAAACC	900 nM
CXCL2	AAGGCATAATGCCTTGTTTAGAGTTAA	900 nM
CXCL5	CGTTGCATGTGTTAAACCACCA	900 nM
CXCL9	ATTTGCCCAAGCCCTTCT	900 nM
CXCR3	TCTTCCTATGACTATGGAGAGAATGAGA	900 nM
CXCR4	CATCTTCTTAAGTGGCATAGTGGGTAA	900 nM
CXCR6	CCACAGCATGACCAGCTTCTACTA	900 nM
CYP26A1	CTGGCTGCCTCTCCAACCT	900 nM
CYSLTR1	CCGCAATCAAGTATATTCCACCTT	900 nM
CYSLTR2	TGTCAACATGTACAGCAGCATTTATT	900 nM
DEF6	TGGAGAAGAGCGGCAAGGT	900 nM
EBI3	CACATCTTTCATTGCCACGTACA	900 nM
EPX	TGGCCTCCCAGGGTACAAT	900 nM
ETS1	CCCGGCAGTGGACAGAGA	900 nM
ETS2	TTGGCAAGGAGCGCTTTC	900 nM
FCER1A	ACTATTACTGGCTACAGCTTCATATCCC	900 nM
FCGR3B	TGGGACCGGTTGCTTGAG	900 nM
FOXP3	CCCTGCCCTTCTCATCCA	900 nM
GATA3	TCTAGCAAATCCAAAAAGTGCAAA	900 nM
GCNT1	CACAAAATTGAAATGCTTGACAGACT	900 nM
GPR44	CTCCCTGCCCTTCTTACCTA	900 nM
HAVCR2	TCTTCAGAACCCATGTTTTACA	900 nM
HDC	GGACAGCATCTTTGGAGACATAGAG	900 nM
HLX1	TTGCTCCTTCCCCCTGG	900 nM
HMBS	GCACGGCCATGTCTGGTAAC	900 nM
HNMT	AAGCATTGGAGACACAAATTCTGA	900 nM
ICOS	CACGGGCATGAACCAAGTC	300 nM
IFNG	TGGTAGCTCTGGGAAACTGAATG	300 nM
IGHA1*	CTTGGAACAAAGGAGAGACATTCTC	900 nM
IGHE	ACCACCAGGCCCCACAA	900 nM
IGHG1*	GGGAGCCGCAGGTGTACA	900 nM
IGHG2A*	TCCAAGACTCCGGGTAAATGA	900 nM
IGHG2B*	TCCAAGACTCCGGGTAAATGA	900 nM
IGHG3*	GGTGGACAAGCGTGTTGGA	200 nM

IGHG4*	GGGAGCCGCAGGTGTACA	300 nM
IGHM	GCACAAAGGGCTGAACTACGA	900 nM
IGJ	TGTAAGTGTGCCCGGATTACTTC	900 nM
IL10	TGAGAACAGCTGCATCCACTTC	300 nM
IL12B	TCTTGGGAGGGTCTGGTTTG	300 nM
IL13	CTGACCACCAGCATGCAGTACT	50 nM
IL13RA1	CGAGTCTGCTGTTACTGAGCTACAA	300 nM
IL13RA2	ATTTTAAGGAATGCACAGTAGAGTATGAA	900 nM
IL18	CGTGTTTGAGGATATGCCTGATT	300 nM
IL18R1	CAGAGAATGGAGAGGAGTATACCTTTG	900 nM
IL1A	CTGAAGAAGAGACGGTTGAGTTTAAA	900 nM
IL1B	TTGAATTCGAGTCTGCCCTGT	900 nM
IL2	ACAGTTGCTTTTGAAGGAAGTTAAGAA	300 nM
IL22	ATACGGCATTGGCTTAGCTTTT	900 nM
IL23A	GAGAAGAGGGAGATGATGAGACTACA	900 nM
IL2RA	AAGCGAGTTTACCACTTCATGGA	50 nM
IL4	GCCGGCCTCGACTGT	300 nM
IL4R	GCAGCGGCATTGTCTATTCA	300 nM
IL5	GACTGGTGGCAGAGACCTTGAC	300 nM
IL5RA	CAAGGATGCCCTGAGGA	900 nM
IL6	AATGTCGAGGCTGTGCAGATT	300 nM
IL8	CCGTGTCAACATGACTTCCAA	300 nM
IL8RA	GCCCTGCCCATCTTCATCTT	900 nM
IL8RB	GCCCTGCCCATCTTCATCTT	900 nM
IL9	CCTGTGAACAGCCATGCA	900 nM
INDO	CTGGTTTTCGCTATTGGTGGAA	300 nM
IRF1	ATCCAGCCCTGATACCTTCTCT	900 nM
ITGB1	TGCCGGGTTTCACTTTGC	900 nM
ITK	GGTTCGTCTTGATGACCAGTAC	900 nM
KIT	CCCTAATGTCTGAACTCAAAGTCTTAAG	900 nM
KITLG	AAAAAGATTCCAGAGTCAGTGCACA	900 nM
KLRB1	TTTATAAACACTGGAATGACAGTCTAGCT	900 nM
LILRB4	GGAAGCCCAACTCCCTGGTA	900 nM
LTC4S	TGAAGGACGAGGTGGCTCTT	900 nM
MAF	CAGTTATAAAAATGGCATTACTGCACA	300 nM
MRC1	GGATGGCTCTGGTGTGGAA	900 nM
MST1	GGGCACTGTGGCCATCA	900 nM
MST1R	CCCCACGAGCGGGTAGT	900 nM
MUC2	GTGCAGGTGCAGGTCAACA	900 nM
MUC3A	AGTGGTTCGAGATCTGGGATGA	900 nM
MUC5AC	TGCTCCTGGTCCAAGTGGTT	900 nM
NFATC2IP	AAGCACCAGATGCTGGAAGTC	900 nM
NOS2A	CGTTATGCCACCAACAATGG	300 nM
PDCD1LG2	GGGCAGTATCGCTGCTTCA	900 nM
PF4	GCTGCGTGTGTGTAAAGACCAT	900 nM
PIAS1	GCTATATTAACACATCCCTCATCCAA	900 nM
PIAS2	GAAGATGATCCGAGCTGCAGTT	900 nM
PIAS3	GACCTACCCCGACCAAGAA	900 nM
PIAS4	ACCTCACCCACCTCATGTACCT	900 nM

PIGR	AAGGGCCAGGGAGACTGAGA	900 nM
PPBP	TCAGGGCAGGAGCTCACTGT	900 nM
PPIA	GCCATGGAGCGCTTTGG	900 nM
PRF1	TTCGCGGCCAGAAAGAC	900 nM
PTGS2	CTGAACACCTCCGCTTTGC	900 nM
RAI17	AATCCTGCCAACTTCCACAATG	900 nM
RETNLB	GCCTTTCTATAGGATGAAGCCAACT	900 nM
RPL32	TGGAAGAGACGTTGTGAGCAA	300 nM
RUNX1	TGAGTCAGCCTTTCTCCTGTGTAG	900 nM
SCNN1G	GCTGCCTACTCCCTGCAGATC	900 nM
SLC11A1	GGCCGTGGGCATCGTT	900 nM
SOCS1	TTCTTCGCCCTCAGTGTGAA	900 nM
SOCS2	GGGTCTAACCGTGGACATTAC	900 nM
SOCS3	CCCCTAGAAGAGCCTATTACATCTACTC	900 nM
SOCS5	ATGTACCTGGAAAATAAACCTCTTGG	900 nM
SOCS7	TCTTATATCCGAAAGTTCTACTACTATGATC	900 nM
STAT1	CACAGAAATCAATTCAGTCTTGATGTATC	300 nM
STAT4	GAAAACCCTCTGAAGTACCTCTATCCT	300 nM
STAT6	CCTGGGTTGGTGAAGACATGT	300 nM
TBX21	TGGACCAACTGTCAATTGCT	300 nM
TFEC	TGCCAACAAATTGACTCTGTCTCA	900 nM
TGFB1	AGGGCTACCATGCCAATTTCT	300 nM
TMED1	GCGGAAGCAATGTTTCTATCAGT	900 nM
TNF	TGGCCCCTTGAGCATCA	300 nM
TNFRSF18	GTCCCAGCTGCTCCCAGTTT	900 nM
TNFRSF4	TGGACCAACTGCACCTTGGT	900 nM
TNFSF18	TTGGAGGCTGAAGATACTTCAGAA	900 nM
TNFSF4	AGGACGAAGACTCTTGAGGAACAA	900 nM
TNFSF8	TTCCAAGTCACATGATCCAGGAT	900 nM
TNFSF8	TTCCAAGTCACATGATCCAGGAT	900 nM
TPSAB1	ACCGGCCTGGCATCTACAC	300 nM
TRA@	CCTCCAAAACCTGTCAGTGATG	900 nM
TSLP	GCATCAGGGAGACTCCAACCT	900 nM
TXK	GTAGAGCTGAACGAGCCTTGAGT	900 nM
UBC	GCGCACCTGTCTGACTACA	900 nM
VTCN1	TTTGATAGAAAAGAATGCTTTGTTTCTAG	900 nM
XCL1	CGAAGTCCTACACAAGAGCATCTG	900 nM
XCR1	TCTTCTGCAAGCTTCTCAACATG	900 nM

Reverse Primer

TGCTGACCTAGAGCCACCATAG	900 nM
GTAGGTGGGAATGTCTTCTTTGCT	900 nM
CAGAGCACCACGAGGAAGGT	900 nM
CCACCCAAATGACACAGAGATCT	300 nM
TTCCTCATTTTGCAGACTAAGTCAAG	900 nM
GCACGGTGCAGTAGGTGATG	300 nM
CTTCCTCTGGTTCATCTGAGTAGT	900 nM
CCTGAAAAGTGAGGAATTTGAAGTG	900 nM
GGGATCTTCTTTCTGGTCACATTA	900 nM
CATCAGGGTTGGTGCAGATCT	900 nM
GGAATGGCCCCTTTGAAGTAC	900 nM
GAAAGGCTCGAACCAGATTCC	900 nM
CCGCGATGGTCTTGAAGATC	900 nM
GGGTGAAGAATATGGTCTGTATATCG	900 nM
CAGATGGCGCATCAGTTCCT	200 nM
GCAGACACTGTCTCCACGTT	900 nM
TGAAAGATTATACTAACGACCAGTGA	900 nM
TGATCCTAGCGGAGGCTTTC	900 nM
GCAGGCGCCACTTAATGTG	900 nM
CCCATGTTTCCTGCGGTTT	900 nM
GCAGACACTGCGTCGAGACA	900 nM
TGAGGGCTGACACAGATTCTTCT	900 nM
CATTGAAAATAAATAACCTCAATTAATACTATAAA	900 nM
CACGAAGTTGCGAGGAAGCT	900 nM
CCCGCACCCATTTCTTCTC	900 nM
CGGCTTTGGTCTTGAAGATCA	900 nM
GCCGATCAGGCCAATGAC	900 nM
CGCGATGGCCACGTATC	900 nM
GAACACAGCGTGGACGATAGC	900 nM
AGAATGGAAAGAACCAGCTCTGTCT	900 nM
CCTTCCATCTTGTGGAGTTGAAA	900 nM
CGTCGTTTGATAATCCATTTTGC	900 nM
TTCAGAAAGTAGCTCCGGA	900 nM
ACTTGGCCGCGCTGTATG	900 nM
TGCTGTGTGAACCCTATAATCTATGC	900 nM
TTTTGCGATATGGAGCATTGAC	900 nM
ACGCTGCGCACATCGAA	900 nM
GCCATACTTGTGGTGAACGA	300 nM
TGGTTTTATCAAAGGCGTTACTGA	900 nM
CCCGGAGTCGGTACTTCAAG	300 nM
CACACAAGTGGTGTCTGTTTTCG	900 nM
TGCTGTTTTACTACTGGCCTCG	300 nM
TGGTGTGGAGCAGAAGCTTT	900 nM
GCCTGTCACATTGAAATCCAGTT	300 nM
TGAGCCCTTGTCTTGATTTG	50 nM
GCTTGGGTGGTGGCGTAGT	300 nM
TGGTAATCGGCATATTTTCTTCTTG	300 nM
TAAGAGGCAGGAGATCATCCAAAA	900 nM

AAAGTTCCATCCTCCAACAGACA	900 nM
ACCCACTGGTTCCTTGAC	900 nM
CCCATACTGGCGCAGAAATT	900 nM
CATTTGCAAGAGGAGCTGAACAC	900 nM
GTTTTCTTAAAGTCTTCAGAATCTTGGA	900 nM
AGCCACACACAGGGCACTGT	900 nM
AGTCCAGGGCCCGTCATG	900 nM
GCCTTATACCTCCCATAACAATATTTAAAATA	900 nM
TTGGATGGTGAGGTTCACTTTG	900 nM
TGCAGACTCTGGTAGGCAAACA	900 nM
GTAATGAGTAAAATTGCTGCTCAGAATAC	900 nM
GACATCTTTTCTCCCCATTCTTTT	900 nM
CTTTCTCAATATCTGCCACTTTCACT	900 nM
AACGTGGCTCTCAAAGAATCG	900 nM
CTCATTCCAGGCGTTGTACCA	900 nM
TCCCTGGCCTCAGACTTAGC	900 nM
TTATTTGTAAAATTACATCAATAAATATCCAAA	900 nM
TCACTTCTGCCTTGGAGCACT	900 nM
GCTGACCTGTTTCTCCCACTCT	900 nM
AGCACGAAGAGGAGGCTGTAGA	900 nM
CCGTCATGCTTCTCAGTTTCTTC	900 nM
GTCTTTCACAAGTTTCCAGAAGTTCTT	900 nM
GCTGAAGGCCTGCATAATCAC	900 nM
GGTATGCTGACTTCTCATGATATGTTTT	900 nM
CCGGAAGGGGTGAACAGTT	900 nM
ATGAGGGATGTGCAGGACTGT	900 nM
ACCATGGAGAACATCAGGACATC	900 nM
CAGGAACTTCCTCGCCAAAG	900 nM
CTTTCAGGCTGAACTCATTGACA	900 nM
TGTCTTTTCTTGGTTTTCTTTGATCA	900 nM
CTGGGTTGAGATCAGTAGCCCT	300 nM
TTGAGATGAGGGTCCCATTCC	900 nM
GTGGCCCGGATGTGAAAA	900 nM
GGGTTGAACGAGCTGCTCTT	300 nM
CTGATTTTTTGTCCACGTGAATG	900 nM
GAAGAAGATGGAGGAGTGCAGCT	900 nM
ACGTAGGCCCTTCCAGAGAT	900 nM
GGGTAGTAGGCGTGCATATGG	900 nM
AGGATGTCCGCGATGCA	900 nM
CCACCACACTGTCCGTTTGTAT	300 nM
CCTGGGTATTGAGCCCGTACT	900 nM
GGAGTCAAATCAAGTCCAGGAAATA	900 nM
GGCTTTGCGCTGGATCTG	300 nM
ACGTGTTCACTTTGGGTTTGG	300 nM
GATCACCTCGCAGGCAAATT	900 nM
TGCTCTTCCACTCAACATGGAT	900 nM
CCCGGGCGATATGTACACA	900 nM
GCCCGGGACGTATGTACACA	900 nM
GCCCGGCCACTTCACA	200 nM

CTCCGGCTGTCCGTTTCTT	900 nM
GATGGCGAAGACGGTGATG	900 nM
TCTGATGTTTCTCTCCACAATGTCTT	900 nM
TCTGGTCCTTCGTTTTGAAAGAAA	300 nM
AAGCTGTTCACAAGCTCAAGTATGA	300 nM
GCTGCAGTCGGAGATGTTGA	900 nM
TCCAGGGAGCCAGGTACAC	900 nM
CCCATCTTTGTAATGTAGATTCTTAGTAATG	900 nM
TGGTTACTGCCAGACCTCTAGTGA	300 nM
GGATCTCCTCAACAACAGCTCTTC	900 nM
AAGTTGTATTTTCATGTTGCTCTGGAA	900 nM
CCCAGGAAGACGGGCTTT	900 nM
CCTGCTTGGGCATGTAAAATTT	300 nM
GAGCGCTGCTACCTGGTGA	900 nM
GGTGGATCCTTTGCAAGCA	300 nM
GGCAGACCCATCCCTGAAC	300 nM
TCCGCTCAGGAGGCTCTTC	300 nM
TCTTCACAACAGCAGCTACAGCA	900 nM
CTTCAATGCATAGTTGGTGATTTGT	300 nM
TGCTGTATTCTTGGCATTCTTCA	900 nM
TGGTGGCTTTGTCTGGATTCT	900 nM
GCCTCACAGAGAGCTGCAGAA	900 nM
GTATTGGCGCCAGATCCT	900 nM
TTGTATTGGCGCCCATGTC	900 nM
GGAAACTTTCCAGGAGACTCCTC	900 nM
GCATCCAGGTCTTCACACTGTATT	300 nM
GGCCTGTTCAATGTCCAAGTC	900 nM
GTGACAATGTCCATCATTGGTAAA	900 nM
CTATAGCGATTGAAAGAGAAGACTTCTG	900 nM
ATCACCATAGCAACAATATTCTGTAAT	900 nM
CTGCTACTGCTGTCATTCCCTAAGG	900 nM
TGTATGAGTCTCAATTCCTCATTATCTTG	900 nM
GCATCACTGGGCTCTGACCT	900 nM
CCTGCGCGCCGAAAT	900 nM
AACATTTACTGATTATTGCCTTGAAAAC	900 nM
AATGCTGGTCAGTGGATCTTTATTC	900 nM
CGGCAGAAGTTCTCCTCAA	900 nM
GATTCGATTCTGGCCTCATC	900 nM
AGAGGCCGTTGTAGGAGATGAG	900 nM
CCAAGGCCACATGGAGTT	900 nM
GGAGGATATTGCTGTAGGTCTCAAA	900 nM
TCCCATGGCCTCCTCGTA	900 nM
AGACCCGGAAGTCGTGCTT	300 nM
TCTTTATTTTCTTGTAGGAAGCTTTGACT	900 nM
GGTCCGGCCCCAATCA	900 nM
GGAAAGAAATCTAATCCTTGTAAGTCATAA	900 nM
TCATTAACAGACTACTCAGTACCATTCCA	900 nM
GGCTCCGTAGCACCGAAGA	900 nM
AAGTACAAGGCCACAGAGTAACTCTTG	900 nM

TTCACCATCCTTCACTGCTCTGT	900 nM
TTCTGGATCCAGGCAGATTTTC	900 nM
TTATTAGATTTGTCCACAGTCAGCAAT	900 nM
CTGTAGAAGCGACACTCCACTGA	900 nM
AAGCACATCGCACACTCTATTATGT	900 nM
TCCAGGTCTGAACCCTTGCT	900 nM
ACAAGGGAGTCTAAGGAACACTGAGA	900 nM
CGGAAGTTTCTGGTACACAATGTAA	300 nM
TGTAICTGGACAGCAAGCAGAT	900 nM
GCGGAGGCAGAGGCTTACT	900 nM
GTACATGTTGGCTTCTCGGATGT	900 nM
GGCCTGGAAGTGCACGC	900 nM
CCCCCATATCTGGAAGAAAA	300 nM
AGGTGGCCGTTGACTGTTTT	900 nM
TGGAGTTTCAAGTTACCTCTTTAAAACA	900 nM
CCTCTTGCTTCTGTTTGGAAATG	900 nM
GAAAGTACTACTCCAGGCCAAAGGA	300 nM
TCACATGGCTGGGAGCTGTA	300 nM
GCCCCTCCAAGAGAAGCTTAG	300 nM
ACGGCTGGGAACGGGATA	300 nM
TGAAGTGTGACAAAGGATCAGAGAA	900 nM
CGGGTTGTGCTGGTTGTACA	300 nM
TGCGATCACCTGGTACTCAGTCT	900 nM
CGGGCTTATCTGAGGTTTGAGA	300 nM
GGCTGCACACGGCATTG	900 nM
TGTCCTCACAGACGGCATCT	900 nM
TTGCCCTTGTAAGCTGTGTT	900 nM
GATGTAGGTGAGACACAGGAGCAA	900 nM
TCACACCTTATCTCTCCTCATCTGA	900 nM
TCACACCTTATCTCTCCTCATCTGA	900 nM
AGGAGGTGACTGGCTTTGCA	300 nM
GGACCACAGCCGCAGTGT	900 nM
CTTCTCATTCCCAGTGCACATG	900 nM
CCATCAACGAAGGTTCCATGT	900 nM
AGATCTGCATCCCACCTCTGA	900 nM
TATAACAAAATGTAATACAGCCATGGTG	900 nM
GCCCTCCTTGATGGTGTAGGT	900 nM
GGCTGACCACGGACAGGTA	900 nM

Probe	
TCCATCACTTGGCAGCTGGGCA	200 nM
AGGACCTGACCTATGCCTCCCTGTGCTT	200 nM
CCTTTGAGCGGGTCTACACTGCCAAC	200 nM
TGGCCATGCCAGGGTCCACC	150 nM
CGAACCATGTCAGCAAAGAGCAAATCA	200 nM
CGTGGGCTTCCTGCTGCCCT	200 nM
TCTCAGGCAGGGCCCCGGCTTC	200 nM
AAAACAGCAGTGTCCCACAGGCCTG	150 nM
ACCCAGGTGCTTGCTTAGCCAGCTTC	200 nM
TCATCTTCATACCAAACGGAACCGA	200 nM
AGGCAGCACTCCCGGCCA	200 nM
CACAGACAGGCAGCAGTCTTCAGCATC	200 nM
TCACCAGCAGCAAGTGTCTAAAGAAGCA	200 nM
AGTCAGAAGCAGCAAGCAACTTTGACTGC	200 nM
CTCGCCCCGGAAGCGCTCTC	900 nM
CTTCAAGCAACTGAGGCAGGCCCTA	200 nM
TGTCATCTTCCTACCAAGAAGGGGC	200 nM
CCGCTTGGCGTCCAATTTCTTCATG	200 nM
TGAGGACTGCTGCCTGGCCTACCAC	200 nM
CACCAAAAAGGCCACAAAGTCTGTGCA	200 nM
CACCTCCAGGCCTTCGTGCTTCA	200 nM
ACTTGGCTGCTGTATCCTTCATGTCAA	200 nM
TTGCCAAACAGCCACTCTCTGGGACTC	200 nM
CCAATGGGCTCAGACCCTCCCAC	200 nM
TGGCACACACCTGGCGTTCTTTC	200 nM
TCACCAACAGCCAGTGTCCCCAGG	200 nM
TGGGCCCCAAAGGCCCTCTC	200 nM
CGCGATGGCCACGTATC	200 nM
CGGAATCTTCTTCATCATCCTCCTGACAATC	200 nM
CAGCAGAGAGTTCTGCTCTCCCGTT	200 nM
CTGAGCGCAACCATACTACTGCAAAACC	200 nM
CCCTTCAAGAATCTCTCCCGGTCTG	200 nM
CCGGTGCTCTACGCCTTCATCGG	200 nM
CATCCTCTTCCTCCTGACCCTTCCCTTC	200 nM
AGGTGTTTCTTGAAGTCTCGCCCATGA	200 nM
CGCTTGTAGTCGGCACCACCATAGCT	200 nM
CCCTGCTCGTTGGCCATCTGC	200 nM
CAACCTTAGCTGCAAGTACACCTACAATCTTTCTC	150 nM
CATTGAGAAACACCTGCACCATCCC	200 nM
CCATGGATCCTTCCCTGATCATCAA	200 nM
CAGCACAAATACTGCGACCCCAACC	150 nM
ATCCTCAAATTGCGGCACATGTCATAAG	200 nM
CCAAGAAAACAAAGAAGTGGACCTTGCC	150 nM
TCCAAGATCCTGAACTGAGCTCTACATGA	200 nM
CCACCTGGACCCTGAGACTCCACAAC	200 nM
CAGCAAAGCCCACCAAGACGCC	250 nM
CCACCACTGCCAGCCCACC	250 nM
TGGAGAATCTATTAAGAATCCCACCTGCTTTCA	200 nM

AACACACTCAAGAACAGGAACCCCAACCT	200 nM
CTCCAGGATCAGCAGGTTCCCTACGC	200 nM
CGCCAGACTTTTCATCACCTCAGTCATCA	150 nM
GGCTGTTCCAGCAAAGCTGCCC	200 nM
CACTTCCCATGTGCTTCGGAGATTGC	200 nM
CACTGCCCATCTGTGTGTGCCAG	200 nM
CCCTGCTGTCTTCACCCGGATCTC	200 nM
CACTCTTGGCATACTTCCAGATGTATGTGAA	200 nM
TGCACTGGCACCTCCACCGAAA	200 nM
CAAGGAAGGCCAGCAGCCCCA	200 nM
CCCGCCTGCTCCTTTGTGATTGAG	200 nM
CTTGCCACATGTTGAGATCATTGCCAC	200 nM
CCAATGCAAAGACACCTTCCCGCTT	200 nM
CCTCGTGCTGACCGCGCTCTG	200 nM
CCCAAGCTGCAGAGCACCAAGC	200 nM
ACACATCCACTGTGGGCCACAGTCTG	200 nM
CCTCTCTATTTTCAGGACAGAGCGGAAACAC	200 nM
CCCGGATTCATCCCAAGATGATCA	200 nM
ATCCCCATTCTTCATTGTAGCAATGACTTCC	200 nM
CTTCGACCGGGCCTTCTCGCC	200 nM
CTGGTAACCCATGACCAGGATGACCAATC	200 nM
CCTGCCTTAACCCTGTGCTCTATGCCTT	200 nM
ACTCCTCGCACAAGCAGCGCAAGA	150 nM
CACAAAGCCATTGCCGAAGAAACCC	200 nM
CCAGGAAACGCACAACACTCAGCAC	150 nM
CAGCTCAAGGTGCTGTCCCACAACC	200 nM
CCAGAGGCCACCAGCTGCACC	200 nM
AGAGCCACAGAAGCGCCTCCAA	200 nM
CCCACATCACCCAGTCCCGAACAT	250 nM
CCCAGAGAATGTCACCCACAAAGTCAGG	200 nM
TCCACAACAAACAGAATCGCCACCA	150 nM
CCCTGGCACTTCAGAGTCACAGAATCCT	200 nM
AGCCAGAGGACTTCTCAAGCACTGCC	200 nM
TCCTCCAGCGTGTCGTGCACCT	150 nM
CTGAGGGCCATCTATATGCCTCAGAATTTCTATT	200 nM
CACGAGTGGCCACGGCCA	200 nM
TCCTGCCCTTGCTGCTACTCCTCACA	200 nM
CAATGTACCACCCAGGCATGATGATTC	100 nM
CGCTGCCGTCAAGAAACCCTCCT	200 nM
CATCTTTGGGCTGTTTTCTTCCGCC	200 nM
TGCAGGTGAAATTGATCTTCAAATTCTCTCCA	200 nM
TCTCTCCAACCTCGAAGTGCAAGATTCCC	200 nM
CTTCGAAAAGCTGATTAATAATTCCGGTAGATAATCTC	200 nM
AGCGCGCTAACCGCCACCATC	150 nM
CCTCCTTCTTCGTCTACAGCCGCCT	150 nM
CTGTCCAGGAGCAAAGTCACGCTAACCT	200 nM
CCACTCGCTGCACCCCTCAAGC	200 nM
TGCTCTTGGGTCCAAGAGCTCACCT	200 nM
CAAAGACCAAACCACCATGTCCCATATGC	900 nM

CTGTCCAGGAGCAAAGTCACGCTAACCT	200 nM
CTCTCTGTGCACCTCCAATCCCAACTCT	100 nM
AGGATCATCCGCTCTGCTGAAGACCC	200 nM
CAACCAGCCTGCCCCACATGC	150 nM
ACCAGCAGCTTCTTCATCAGGGACATCA	200 nM
TGCCGCCCTGGAATCCCTCA	150 nM
CGTTTGGCACAACCTGCGCTACATG	200 nM
CGAAACATTGATAGTGAAAGCTGGAAGACGA	200 nM
TGACTGTTCAGATAATGCACCTCAGACCGT	100 nM
CAAATGTTTCTCCAACACCCTGGGCA	200 nM
CAGAAGAAGAAATCATCAAGCCCAGATCAGC	200 nM
CAACTGGTACATCAGCACCTCTCAAGCAGAA	150 nM
CGAGAATGCTGATCTCTCCAGGATGCTC	150 nM
TGAACTTCACCCTTGAAGAAGTGCTGTTCC	200 nM
CTGAGGATCACAGCCATCCCCGC	100 nM
CAGACAGTTCGGTACCAGTGCCTCCC	100 nM
CTTCGGCACATCTACAGACACCACACG	200 nM
CTGCCACCTGTGCGGCCACC	200 nM
CTGCTCTCCATTTCATCGAACTCTGCTGAT	200 nM
ACGCAGTATTTCTCTACTATAGGTACGGCTCTGTG	200 nM
AGCACTGATCCAGACCCTGAGGCAA	200 nM
CTGTTGCCTTCTTGGCAGTTTTCTGC	200 nM
CGTGAAGCCTACCATCCACCCTACTCC	200 nM
CGCAGGGCCATCCATCCACC	200 nM
ACCACAGTAGGCAACACGCTCATCTTTCTG	200 nM
CTGCAATCAAGGTGATCCCCACTCTATTCA	150 nM
TGCCTGATGACCACAGCAGCTACACA	150 nM
AACAATGCCACCAAGTTTCCCATCTCC	200 nM
CCAGTTCCACAGGCACCAAATTCCC	200 nM
CCTGCACCATTGGAGGGCCCA	200 nM
CCATTTATGTTACCCCTGTTGCAGCC	200 nM
CTGTTCCACAAAAGAATCCAGTCTGCTGC	200 nM
TCTCCATAACAATACATGACTGAGGCCTACGC	200 nM
AGTCCTGCTGCAAGCCTACTTCTCCCTG	200 nM
AGTTACAGAAAATCCAGTTTCTGCACCACAATACAA	150 nM
TGCCCTCAAATTTCAATGGACAATATCCAAAT	200 nM
ACCACAAGTACACGCCACACTCCG	200 nM
TGACCGAGTCATTGGCAAAGGCCA	200 nM
CATCAACTACGTGGTGGACATCCCCG	200 nM
CCATCTTTAACTGTTCTGTCTCCTCAAAAACC	200 nM
CGTGGACTTCCCGTCCCCCG	200 nM
CTCCTCTCAAGACCCTCATGTCCCGC	200 nM
ATCAGGTTCGGCCATCACCGTG	200 nM
CGCCTGGGACTACAAGTACCTGACTCTGAA	200 nM
TCAGCCCCAAGCATATCTCCAGCCTA	200 nM
CATCCTTTCCACATGACACCCATGCC	900 nM
CTCCTGGCAAATCTGATGACATGCTTGATA	200 nM
CTACCTGGAAGCAAAGGAGTCCTGACATC	200 nM
CTCGGCCACCAACCGCATCACT	200 nM

TCCTGGATCCCAGCCTCATTGCA	150 nM
TCATTCTTCAGCGTGGCTATCACTTCGAC	200 nM
TGATCTTCTTGCTGGTCTTGCCATTCT	200 nM
CACCAGGACCAGTACCGCTTCAGCC	200 nM
CAGACCAGGCACCAGACCAAAGACCTC	200 nM
CACCGTCAAACAGCCCATCAGGC	200 nM
CCTCATCCTCCTTCTTCAGTTGATAATCGCA	200 nM
ATTTGTTGCACATTAGCAGCACTTCAAGCTC	200 nM
CCAGCAGAACAGAGACATTGCCAACC	200 nM
CGCACCCACATTTCTCCACCATCTT	200 nM
CGCCATCATCATGCCCAACAAC	150 nM
TTCGGGCCCCACAAGCATCC	150 nM
TCTCCCTTCTACCATGTAGAACCCTTTGGC	150 nM
CTGGTGTTGAGCCGGCCCTC	150 nM
TGCTTGATATATAGTCTTTCTCCAAAAATCAGTACC	200 nM
AGCTGCGCTTCCTTTAGAGACAGGTATACCT	200 nM
CCTTTAGGGCCGTCAAGTTCCATAGGTTT	100 nM
ACATTCCTCAAAGACAAAGCCTTCGGTAAACA	200 nM
TGCTGCCTCCCACTGAACAGGACCT	200 nM
ACCACTACTCTCCTCTCCTCCCCAACCAGT	150 nM
CAAGCCCTGAGCTCTGTGATCAAGCTATG	200 nM
CCTAGACACTCAGTACAGCAAGGTCCTGGC	200 nM
CGCCGGCCAACGCAAGCCT	200 nM
CCCTCTGGCCCAAGGACTCAGATCA	150 nM
CACGTTCCCTGGGAACAAGACGC	200 nM
CGCCTGCAGCGTTCGCTTCC	150 nM
CTTGATTTAATTTATGGCCAAGTGGCTCCCA	900 nM
CCCAGACCCTGAATTACGGAGGCC	150 nM
CCCATCTCTGTTCCAAGAAGGATTCTCCC	200 nM
CCCATCTCTGTTCCAAGAAGGATTCTCCC	200 nM
CGCGTCACCCACTACTTGGACTGGAT	200 nM
CATCATCCTCCTGAAAATGGTTGGGTTTAAAC	200 nM
AGCCCATATTCACCCATGTTGTTGCCT	200 nM
CATCACTTTAGCCTCTTCAATGAAATCCTCTTCA	200 nM
AGTCCACCCTGCACCTGGTCCTCC	200 nM
CCACTGCCTCCCTGGCACTTTGG	200 nM
TCTAACTACCCGGCGACTGCCAGTAAA	200 nM
TCTTCTCCATCAGCCTCTACAGCAGCATC	200 nM